Consistent Model for Drain Current Mismatch in MOSFETs Using the Carrier Number Fluctuation Theory

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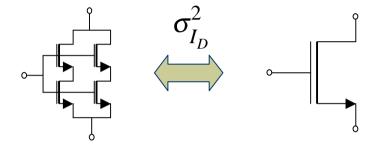
OUTLINE

- Introduction
- Mismatch Channel Model
- Fluctuation of Charge Density
- Number Fluctuation Model
- Mismatch vs. Inversion Level
- Experimental Results
- Conclusions



INTRODUCTION

- Desirable properties of mismatch models: consistency, accuracy, simplicity.
- Consistency :
 series-parallel
 association



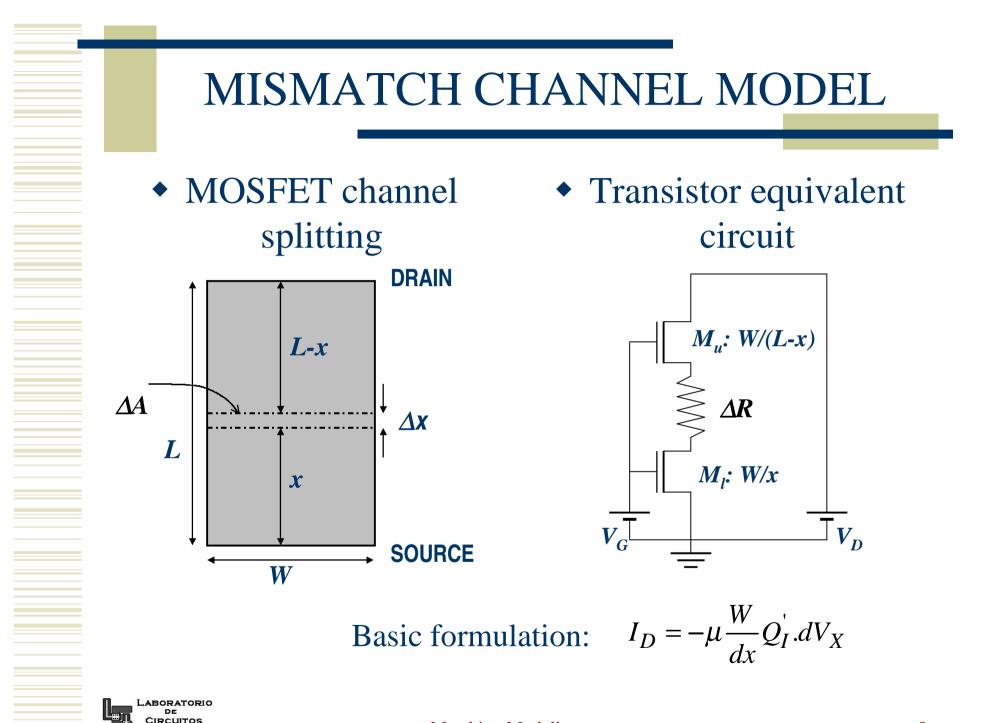
- Consistency : contributions of the randomly varying technological, e. g. V_T, C_{ox} and geometric (W, L) parameters.
- Consistency: local fluctuations in V_T rather than total fluctuation (lumped parameter).
- Accuracy/consistency: model valid for any bias condition.
- Simplicity: simple models, easy-to-extract parameters





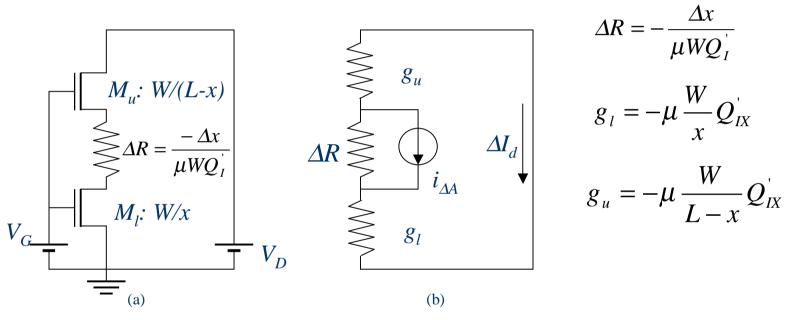
Purpose: A simple one-equation mismatch model for hand analysis & design and circuit simulation.





NTEGRADOS

MISMATCH CHANNEL MODEL



small-signal equivalent circuit

• Mismatch results from local current fluctuation $(i_{\Delta A})$ in the small channel element.



MISMATCH CHANNEL MODEL

• Contribution of local current fluctuation $(i_{\Delta A})$ to drain current (ΔI_d) :

$$\Delta I_d = (\Delta x/L)i_{\Delta A}$$

• The fluctuation of the local charge is the main contribution to mismatch

$$i_{\Delta A} = I_D \frac{\Delta Q_I'}{Q_I'}$$

Total drain current variance is the sum of (uncorrelated) individual contributions

$$\left(\Delta I_D\right)^2 = \frac{1}{L^2} \int_0^2 \left[\Delta x (i_{\Delta A})^2\right] dx$$

contribution of the channel element to total current



FLUCTUATION OF CHARGE DENSITY

• From UCCM

 $\frac{\Delta Q_{I}^{'}}{Q_{I}^{'}} = \frac{-C_{ox}^{'}\Delta V_{T}}{Q_{I}^{'} - nC_{ox}^{'}\phi_{t}}$

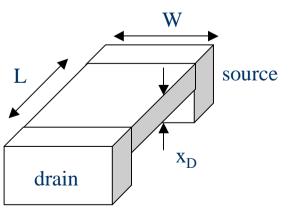
Local fluctuation of V_T
 from Pelgrom's expression

$$\sigma_{VT}^{2} = \frac{A_{VT}^{2}}{LW} \Longrightarrow \overline{\Delta V_{T}^{2}} = \frac{A_{VT}^{2}}{\Delta xW}$$

lumped

distributed

 Poisson statistics for depletion charge fluctuations



$$A_{VT}^{2} = \frac{q^{2}}{C_{ox}^{'2}} (N.x_{D}) = \frac{q^{2}}{C_{ox}^{'2}} N_{oi}$$

 N_{oi} : effective number of impurities per unit area of gate



NUMBER FLUCTUATION MODEL

The previous considerations result for the current mismatch in any operating region

$$\frac{\sigma_{I_D}^2}{I_D^2} = \frac{q^2 N_{oi} \mu}{L^2 n C_{ox} I_D} \ln \left(\frac{Q_{IP} + Q_{IS}}{Q_{IP} + Q_{ID}} \right)$$

with

$$Q_{IP} = -nC_{ox}\phi_t$$



MISMATCH vs. INVERSION LEVEL

In terms of inversion level[†]

$$\frac{\sigma_{I_D}^2}{I_D^2} = \frac{N_{oi}}{WLN^{*2}} \frac{1}{i_f - i_r} \ln\left(\frac{1 + i_f}{1 + i_r}\right)$$

where

$$N^* = \frac{-Q_{IP}}{q} = \frac{nC_{ox}\phi_t}{q}$$

† for long channel MOSFET, from ACM model

$$I_{D} = I_{F} - I_{R} = I_{S}(i_{f} - i_{r}) \qquad I_{S} = \frac{1}{2}\mu C_{ox}^{'} n\phi_{t}^{2}(W/L)$$

LABORATORIO DE CIRCUITOS INTEGRADOS

SUMMARY

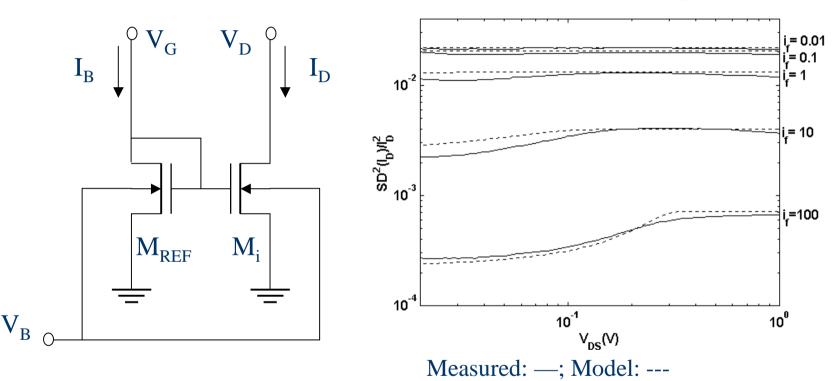
$\frac{\sigma_{I_D}^2}{I_D^2}$	weak inversion $(i_f < l)$	strong inversion $(i_f >> 1)$
linear region $(i_f \approx i_r)$	$\frac{N_{oi}}{WLN^{*2}}$	$\frac{N_{oi}}{WLN^{*2}} \frac{1}{1+i_f}$
saturation region $(i_f >> i_r)$	$\frac{N_{oi}}{WLN^{*2}}$	$\frac{N_{oi}}{WLN^{*2}} \frac{\ln(1+i_f)}{i_f}$



EXPERIMENTAL RESULTS

Test circuit

Saturation level dependence

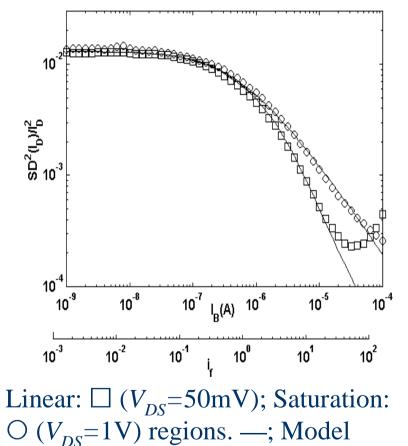


Test chip contains 24 NMOS 30 μ m x 1.2 μ m transistors in the ES2 1.2 μ m CMOS DLM process

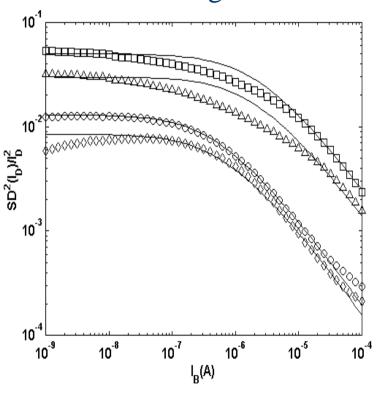
LABORATORIO DE CIRCUITOS INTEGRADOS

EXPERIMENTAL RESULTS





Dependence on bulk-source voltage



 V_{BS} : \Box = -1.8V; \triangle = -1.2V; \bigcirc = 0V; \diamondsuit =+0.3V. (Saturation: V_{DS} =1V).



CONCLUSIONS

- Physics-based approach (fluctuation in the number of carriers) used for derivation of mismatch.
- Use of ACM model resulted in a compact easy-touse formula that is continuous in any operating region.
- Experimental results confirmed the accuracy of our model under various bias conditions.
- Useful tool for designers to predict transistor mismatch in an accurate and easy way.
- Single parameter model (N_{oi}) to interface foundries and designers.

